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In re Patent Application of ) Art Unit: 1765  
Naoaki YAMAGUCHI et al. ) Examiner: A. Alanko  
Serial No. 10/035,441 ) Confirmation No. 4492  
Filed: January 4, 2002 )  
For: OPTICAL PROCESSING )  
APPARATUS AND OPTICAL )  
PROCESSING METHOD )

**CERTIFICATE OF MAILING**

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**AMENDMENT**

Commissioner for Patents  
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**GROUP 1700**

Sir:

In response to the Official Action dated February 21, 2003, please amend the  
above-identified application as follows:

**IN THE SPECIFICATION:**

At p. 1, before the first line of the specification, please insert the following:

*A1* --The present application is a Divisional of Serial No. 09/547,716, filed April 11,  
2000, now U.S. Patent No. 6,336,969; which itself is a Divisional of Serial No.  
08/451,648, filed May 26, 1995, now U.S. Patent No. 6,059,873.--

**IN THE CLAIMS:**

*A2* 1. (Amended) An optical processing method comprising the steps of:  
preparing a semiconductor film over a substrate;  
irradiating a laser light onto said semiconductor film to crystallize said  
semiconductor film, and